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PLEASE USE THIS FOR PTO FORM 1449 REGARDING SCENTIFIC ARTICLES ...

- Regression Calibration Method For Rotating Element'
 Ellipsometers", which appeared in Thin Film Solids, Vol. 234 in
- "A New Purged UV Spectroscopic Ellipsometer to Characterize Thin Films and Multilayers at 157nm", Boher et al., Proc. SPIE, Vol. 3998, (June 2000).
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- "Optical Characterization in the Vacuum Ultraviolet with Variable Angle Spectroscopic Ellipsometry: 157nm and below", Hilfiker et al., Proc. SPIE Vol. 3998 (2000).
- "Feasibility and Applicability of Integrated Metrology Using Spectroscopic Ellipsometry in a Cluster Tool", Boher et al., SPIE Vol. 4449, (2001).
- Four papers authored or co authored by Collins, which describe use of multichannels and rotating element ellipsometers, including rotating compensator, but not in an environmental chamber are:
- "Characterization of Wide Bandgap Thin Film Growth Using
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 to Cubic Boron Nitride", Zapien et al., J. of Wide Bandgap
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- "Automated Rotating Element Ellipsometers: Calibration,

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 Applications for Rapid-Scan Spectroscopic Ellipsometers", An.
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- "Multichannel Ellipsometer for Real Time Spectroscopy of Thin Film Deposition for 1.5 to 6.5 eV", Zapien et al., Rev. Sci. Instrum. Vol. 71, No. 9, (Sept. 1991).